

ABSTRACT OF THE DISCLOSURE

A substrate processing apparatus includes a light source, a plurality of light transmitting windows, and a reaction chamber, in which a substrate is placed.

5 And a surface of the substrate, which opposes the light transmitting windows is processed by using a reaction which occurs when the light from the light source is irradiated into the reaction chamber through the light transmitting windows. This substrate processing
10 apparatus includes a driving mechanism which moves the substrate relative to the light transmitting windows in a direction parallel to the surface. The width of each of the light transmitting windows in the direction in which the substrate moves relative to the light
15 transmitting windows is smaller than the length of the substrate in the moving direction.